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**NATIONAL STANDARD OF THE
PEOPLE'S REPUBLIC OF CHINA**

GB/T 30867-2014

**Test method for measuring thickness and total thickness
variation of monocrystalline silicon carbide wafers**

碳化硅单晶片厚度和总厚度变化测试方法

(English Translation)

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What this standard covers

This standard specifies the silicon carbide single wafer thickness and total thickness variation (TTV) of test methods, including contact and non-contact two ways. This standard applies to a diameter of not less than 30 mm, a thickness of 0.13 mm ~ 1 mm S

Document data

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Standards quoted by this document

GB/T 14264; GB/T 25915.1-2010